



Appl. No. 09/212,726

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

#27
Am dt
H
8/14/03
arey

Application Serial No. 09/212,726
Filing Date December 15, 1998
Inventor..... Klaus F. Schuegraf
Assignee..... Micron Technology, Inc.
Group Art Unit..... 2813
Examiner Kielin, Erik J.
Attorney's Docket No. MI22-1098
Title: Semiconductor Processing Methods of Chemical Vapor Depositing SiO₂ on a Substrate

RESPONSE TO APRIL 28, 2003 OFFICE ACTION

To: Mail Stop Non-Fee Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

From: Jennifer J. Taylor, Ph.D. (Tel. 509-624-4276; Fax 509-838-3424)
Wells St. John P.S.
601 W. First Avenue, Suite 1300
Spokane, WA 99201-3828

RECEIVED
TECHNOLOGY CENTER 2800
AUG -1 2003

AMENDMENTS

Introductory Comments

In reply to the office action dated April 28, 2003, applicant amends and remarks as follows.